

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
MI22-1694SERIAL NO.
09/885,393LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Richard Holscher et al.FILING DATE
June 19, 2001GROUP
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U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
KUTD	AA	4,755,478	07/88	Abernathay, et al.	437	41	
KUTD	AB	4,870,470	09/89	Bass, Jr., et al.	357	23.5	
KUTD	AC	5,312,768	05/94	Gonzalez	437	40	
KUTD	AD	5,439,838	08/95	Yang	437	43	
KUTD	AE	6,001,747	12/99	Annapragada, Rao V.	438	790	
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

KUTD	AR	Wolf, et al. <i>Silicon Processing for the VLSI Era, Vol. 1 - Process Technology</i> , Lattice Press: Sunset Beach, CA, 1986, pp. 189-190.
	AS	
	AT	

EXAMINER

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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.